



6-13-2015

Thickness Measurement on Ti, Au, Pd, and Cr using PVD75 E-beam Evaporator

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Turakhia, Dhruv, "Thickness Measurement on Ti, Au, Pd, and Cr using PVD75 E-beam Evaporator", *Tool Data*. Paper 30.
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Keywords

Thickness, Ti, Au, Pd, Cr

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Thickness Measurement on Ti, Au, Pd, and Au using PVD75 E-beam Evaporator (Graduate Student Fellow Program)

Prepared by Dhruv Turakhia (6/5/2015)

Deposition Rate: 2 Å/sec

Final Thickness Set Point: 300 nm

Default Tooling Factor Xtal 1: 54

Default Tooling Factor Xtal 2: 100

Thickness measurement: P7 Stylus Profiler

Ti deposition

Measured thickness: 306.0 ± 9.6 nm

Au deposition

Measured thickness: 237.6 ± 4.2 nm

Pd deposition

Measured thickness: 265.5 ± 17.8 nm

Cr deposition

Measured thickness: 407.2 ± 16.5 nm